

	Hits	Search Text
1	21466	(mask or reticle) same (substrate or wafer) same align\$6
2	25948	(mask or reticle or substrate or wafer or reference or alignment) near3 mark
3	4457	S1 and S2
4	369	(align\$6) with (numerical near aperture)
5	10603	(lens or projection) with (numerical near aperture)
6	55	ad<="20020716" and S6
7	55	S3 and S4 and S5
8	50	@ad<="20020716" and S6
9	57299	(align\$5 or position\$3) near4 (mirror or reflector)
10	105980	(mask or reticle) same (substrate or wafer)
11	9527	(projection) near5 (mirror or reflector)
12	957	S10 and S11 and S12
13	720	@ad<="20020716" and S13
14	20184	(alignment or reference) near2 mark
15	311	S14 and S15
16	3509	S15 with (mask or reticle)
17	5411	S15 with (substrate or wafer)
18	231	S17 and S18 and S14

OK
11/4/05